

Title (en)

METHOD AND DEVICE FOR COATING HIGH TEMPERATURE COMPONENTS BY MEANS OF PLASMA SPRAYING

Title (de)

VERFAHREN UND VORRICHTUNG ZUR BESCHICHTUNG VON HOCHTEMPERATURBAUTEILEN MITTELS PLASMASPRITZENS

Title (fr)

PROCEDE ET DISPOSITIF DE REVETEMENT DE COMPOSANTS HAUTE TEMPERATURE PAR PROJECTION AU PLASMA

Publication

EP 1115894 A1 20010718 (DE)

Application

EP 99952248 A 19990803

Priority

- DE 9902381 W 19990803
- DE 19837400 A 19980818

Abstract (en)

[origin: DE19837400C1] The invention relates to a method for coating high temperature components (10) by means of plasma spraying. An infrared camera (20) is used to determine the thermal radiation distribution (30) of the component surface (40) and consequently the temperature distribution (70) used to adjust an operating parameter (p) in order to obtain a threshold temperature (Ts). The invention also relates to a coating device used to form a coating (14) and simultaneously control surface temperature with the infrared camera (20).

IPC 1-7

C23C 4/12

IPC 8 full level

C23C 4/12 (2006.01); **B05C 5/04** (2006.01); **C23C 4/00** (2006.01)

CPC (source: EP US)

B05B 7/226 (2013.01 - EP); **B05B 12/12** (2013.01 - EP); **C23C 4/00** (2013.01 - US); **C23C 4/12** (2013.01 - US); **C23C 4/134** (2016.01 - EP)

Citation (search report)

See references of WO 0011234A1

Cited by

DE102014220180A1; US10975463B2

Designated contracting state (EPC)

AT BE CH CY DE DK ES FI FR GB GR IE IT LI LU MC NL PT SE

DOCDB simple family (publication)

DE 19837400 C1 19991118; CA 2340930 A1 20000302; DE 59901219 D1 20020516; EP 1115894 A1 20010718; EP 1115894 B1 20020410; JP 2002523623 A 20020730; US 6537605 B1 20030325; WO 0011234 A1 20000302

DOCDB simple family (application)

DE 19837400 A 19980818; CA 2340930 A 19990803; DE 59901219 T 19990803; DE 9902381 W 19990803; EP 99952248 A 19990803; JP 2000566484 A 19990803; US 76308101 A 20010420